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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO	
10/007,618	11/07/2001	Neil S. Casa	5300-17	4190	
7590 02/12/2004			EXAMINER		
Thomas Langer, Esq.			TRAN, THUY VAN		
Cohen, Pantani, Lieberman & Pavane 551 Fifth Avenue			ART UNIT	PAPER NUMBER	
Suite 1210			3652		
New York, NY 10176			DATE MAILED: 02/12/2004		

Please find below and/or attached an Office communication concerning this application or proceeding.

		Applic	cation No.	Appl	icant(s)			
Office Action Summary			7,618	i .	A, NEIL S.	//		
2	Since Action Cummary	Exam		Art U				
·	The MAIL INC DATE of this commun		v. Tran	3652		44		
Period fo	• •			·		Iaress		
THE I - Exter after - If the - If NO - Failu - Any r	ORTENED STATUTORY PERIOD F MAILING DATE OF THIS COMMUNI nsions of time may be available under the provisions SIX (6) MONTHS from the mailing date of this comm period for reply specified above is less than thirty (3 period for reply is specified above, the maximum sta- re to reply within the set or extended period for reply eply received by the Office later than three months a ed patent term adjustment. See 37 CFR 1.704(b).	CATION. of 37 CFR 1.136(a). In n nunication. 0) days, a reply within the atutory period will apply a will, by statute, cause the	no event, however, may e statutory minimum of nd will expire SIX (6) N e application to become	a reply be timely filed thirty (30) days will be IONTHS from the mail ABANDONED (35 U	considered timeling date of this c			
1)🖂	Responsive to communication(s) file	ed on <u>06 October :</u>	<u>2003</u> .					
2a) <u></u> ☐	This action is FINAL . 2	b)⊠ This action i	s non-final.					
3)								
Dispositi	on of Claims							
4)🖂	Claim(s) <u>1-53</u> is/are pending in the a	opplication.						
-	4a) Of the above claim(s) 10,11,16,20,21 and 35-53 is/are withdrawn from consideration.							
5)⊠	Claim(s) <u>22-34</u> is/are allowed.							
6)⊠	Claim(s) <u>1-7,12-15 and 17-19</u> is/are rejected.							
7)⊠	☑ Claim(s) <u>8 and 9</u> is/are objected to.							
8)□	Claim(s) are subject to restrict	tion and/or election	on requirement.					
Applicati	on Papers							
9)[The specification is objected to by the	e Examiner.						
10)	The drawing(s) filed on is/are:	a) accepted o	r b)□ objected	to by the Exami	ner.			
	Applicant may not request that any object	ction to the drawing	(s) be held in abe	yance. See 37 Cl	FR 1.85(a).			
_	Replacement drawing sheet(s) including		•	-		` .		
-	The oath or declaration is objected to	by the Examiner	. Note the attach	ned Office Action	n or form P1	ΓO-152.		
Priority u	ınder 35 U.S.C. §§ 119 and 120							
	Acknowledgment is made of a claim All b) Some * c) None of: 1. Certified copies of the priority 2. Certified copies of the priority 3. Copies of the certified copies	documents have l	been received. been received ir	n Application No	·	Stage		
13) <u> </u>	application from the Internation See the attached detailed Office action acknowledgment is made of a claim for note a specific reference was included	n for a list of the c or domestic priorit	certified copies n y under 35 U.S.	C. § 119(e) (to a				
_ a	7 CFR 1.78.) ☐ The translation of the foreign lar							
	acknowledgment is made of a claim for eference was included in the first sent							
Attachment	t(s)							
1) Notice 2) Notice	e of References Cited (PTO-892) e of Draftsperson's Patent Drawing Review (P nation Disclosure Statement(s) (PTO-1449) P			w Summary (PTO-4 of Informal Patent A				
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DETAILED ACTION

Election/Restrictions

Applicant's election without traverse of Species A (paddle with opening) in Paper No. 7 is acknowledged.

Claims 10, 11, 16, 26 and 35-57 are withdrawn from further consideration pursuant to 37 CFR 1.142(b) as being drawn to a nonelected Species, there being no allowable generic or linking claim. Election was made **without** traverse in Paper No. 8.

Claim Rejections - 35 USC § 112

The following is a quotation of the second paragraph of 35 U.S.C. 112:

The specification shall conclude with one or more claims particularly pointing out and distinctly claiming the subject matter which the applicant regards as his invention.

Claims 1-9 and 12 are rejected under 35 U.S.C. 112, second paragraph, as being indefinite for failing to particularly point out and distinctly claim the subject matter which applicant regards as the invention.

Re claim 1, the recitation "during at least one of the pressurization and depressurization", found in lines 9-10, renders the claim indefinite because it is not unclear whether "one of the pressurization and depressurization" is the same as "alternating depressurization and repressurization" as recited in line 5 or not. Further, it is unclear what applicant meant by "having a wafer-receiving surface having with openings therein". Does applicant mean "having a wafer-receiving surface with openings therein"?

Claim 12 recites the limitation "said loadlock chamber" in line 3. There is insufficient antecedent basis for this limitation in the claim.

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Claim Rejections - 35 USC § 102

The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

(b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.

Claims 1-7, 12-15, 17-19 (as best understood) are rejected under 35 U.S.C. 102(b) as being anticipated by Adams et al. 6,123,502.

Adams et al. '502 disclose a semiconductor wafer holding system comprising a transfer chamber 12, interposed between ambient atmosphere and an inspection chamber which is at vacuum pressure and subjected to alternating depressurization and repressurization, at least one paddle 52 arranged in the transfer chamber, having a wafer-receiving surface with openings 64 therein, drawing means 60 for drawing the wafer to the wafer-receiving surface of the paddle to thereby inhibit motion of the wafer, wherein the drawing means comprise a vacuum source 60, conduit means 58 for providing flow communication between the vacuum source and the opening, and proving a pressure at the openings lower than the pressure prevailing in the transfer chamber, a valve 62 for opening and closing the flow communication between the vacuum source and the openings.

Re claims 17-19, the apparatus of Adams et al is capable of performing the claimed functions.

Conclusion

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The prior art made of record and not relied upon is considered pertinent to applicant's disclosure. Each of the cited references separately discloses a semiconductor wafer holding system for holding wafers having at least one paddle with openings therein and drawing means for drawing the wafer to the wafer-receiving surface of the paddle.

Allowable Subject Matter

Claims 22-34 are allowed.

Claims 8 and 9 are objected to as being dependent upon a rejected base claim, but would be allowable if rewritten in independent form including all of the limitations of the base claim and any intervening claims.

The following is an examiner's statement of reasons for allowance: the prior art of record fail to disclose or suggest to combine a method for transferring semiconductor wafers between ambient atmosphere and an inspection chamber, maintained at vacuum pressure, through a transfer chamber, comprising the steps of transferring a wafer from the ambient atmosphere through a first gate valve onto a paddle in the transfer chamber while the transfer chamber is isolated from the inspection chamber by a closed second gate valve, providing the paddle with a wafer-receiving surface having openings therein, the wafer being placed on the paddle and over the openings, coupling the openings in flow communication with a vacuum source or pump, controlling the flow communication between the vacuum source or pump and the openings during at least one of the depressurization and repressurization of the transfer chamber to cause the wafer to be drawn to the wafer receiving surface by suction and thereby inhibit motion of

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the wafer during the at least one of the depressurization and repressurization of the transfer chamber, in combination with other limitations as recited in respective independent claims 22 and 27.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Thuy v. Tran whose telephone number is 703-308-2558. The examiner can normally be reached on M-F.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Eileen D. Lillis can be reached on 703-308-3248. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

TVT (TJT)

EILEEN D. LILLIS SUPERVISORY PATENT EXAMINER TECHNOLOGY CENTER 3600

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